

In the Claims:

1. (Currently amended) A light-emitting semiconductor component comprising a monolithically produced sequence of semiconductor layers (2), wherein an area of n-doped semiconductor layers (3) and an area of p-doped semiconductor layers (4) follow one another and a first pn junction (5a, 5b) is formed between the n-doped areas and p-doped areas (3, 4), wherein the first pn junction (5a, 5b) is subdivided into a light-emitting section (7) and a protective-diode section (8) by an insulating section, (6), ~~characterized in that~~

wherein the insulating section (6) electrically insulates the light-emitting section (7) and the protective-diode section (8) from one another in the area of the p-doped semiconductor layers (4),

wherein the area of the p-doped semiconductor layers (4) is provided in the protective-diode section (8) on the side facing away from the first pn junction (5b) with an n-doped semiconductor layer (9) which forms a second pn junction (10) with the area of p-doped semiconductor layers (4) in the protective-diode section (8) and is electrically conductively connected to the area of p-doped semiconductor layers (4) in the light-emitting section (7), and

wherein the first pn junction (5a, 5b) has a larger area in the protective-diode section (8) than in the light-emitting section (7).

2. (Currently amended) The light-emitting semiconductor component as claimed in claim 1, ~~characterized in that~~ wherein the area of the first pn junction (5a, 5b) is larger in the protective-diode section (8) than in the light-emitting section (7) by at least a factor of 100.

3. (Currently amended) The light-emitting semiconductor component as claimed in claim 1, ~~or 2, characterized in that~~ wherein the sequence of semiconductor layers (2) is applied to a semiconductor substrate (1).

4. (Currently amended) The light-emitting semiconductor component as claimed in claim 3, ~~characterized in that~~ further comprising a first contact metallization (11) is applied to a side of the semiconductor substrate (1) facing away from the sequence of semiconductor layers, (2) and a second contact metallization (12) is applied to part-areas of a surface of the sequence of semiconductor layers (2) opposite to the semiconductor substrate (1).

5. (Currently amended) The light-emitting semiconductor component as claimed in claim 1, wherein ~~one of the preceding claims, characterized in that~~ the area of n-doped semiconductor layers (3) is only partially ~~not~~ interrupted by the insulating section or is not interrupted at all (6) ~~at least in parts~~.

6. (Currently amended) The light-emitting semiconductor component as claimed in claim 3, wherein ~~or as claimed in one of claims 4 or 5, with reference to claim 3, characterized in that~~ the insulating section (6) extends from a surface of the sequence of semiconductor layers (2) opposite to the semiconductor substrate (1) into the area of n-doped layers (3).

7. (Currently amended) The light-emitting semiconductor component as claimed in claim 1, wherein ~~one of the preceding claims, characterized in that~~ the light-emitting section (7) is formed by a vertical cavity surface emitting laser (VCSEL).

8. (Currently amended) The light-emitting semiconductor component as claimed in claim 7, ~~characterized in that~~ wherein the first pn junction (~~5a, 5b~~) is arranged between a first sequence of Bragg reflector layers and a second sequence of Bragg reflector layers, each of which has a multiplicity of layer pairs, and the two sequences of Bragg reflector layers form a laser resonator, one of the two sequences of the Bragg reflector layers being semitransparent for the laser radiation (~~18~~) generated in the pn junction (~~5a~~).

9. (Currently amended) The light-emitting semiconductor component as claimed in claim 8, ~~characterized in that~~ wherein in one of the two sequences of Bragg reflector layers, at least one current aperture (~~14~~) is provided for spatially limiting an operating current flowing through the first pn junction (~~5a~~) in the light-emitting section (~~7~~) during the operation of the vertical cavity surface emitting laser.

10. (Currently amended) The light-emitting semiconductor component as claimed in claim 4, wherein ~~or as claimed in one of claims 5 to 9, with reference to claim 4, characterized in that~~ the second contact metallization (~~12~~) partially covers the surface of the light-emitting section in such a manner that an uncovered area remains as light exit opening (~~17~~).

11. (Currently amended) The light-emitting semiconductor component as claimed in claim 1, wherein ~~one of the preceding claims, characterized in that~~ the insulating section (~~6~~) is constructed as trench (~~19~~).

12. (Currently amended) The light-emitting semiconductor component as claimed in claim 11, ~~characterized in that~~ wherein the light-emitting section ~~(7)~~ and the protective-diode section ~~(8)~~ have a mesa-shaped structure on the side of the trench ~~(19)~~.

13. (Currently amended) The light-emitting semiconductor component as claimed in claim 11, wherein ~~or 12, characterized in that~~ the trench ~~(19)~~ is bounded by areas which are provided with an insulating layer ~~(16)~~.

14. (Currently amended) The light-emitting semiconductor component as claimed in claim 13, ~~characterized in that~~ wherein the trench ~~(19)~~ is filled with a material from which the second contact metallization ~~(12)~~ is formed.

15. (Currently amended) The light-emitting semiconductor component as claimed in claim 1, wherein ~~one of claims 1 to 10, characterized in that~~ the insulating section ~~(6)~~ is formed by an implantation, diffusion or oxidation process.

16. (Currently amended) The light-emitting semiconductor component as claimed in claim 1, wherein ~~one of the preceding claims, characterized in that~~ n doping and p doping of the semiconductor layers are exchanged for one another.

17. (New) A light-emitting semiconductor component comprising a monolithically produced sequence of semiconductor layers, wherein an area of n-doped semiconductor layers and an area of p-doped semiconductor layers follow one another and a first pn junction is formed between the areas, wherein the first pn junction is subdivided into a light-emitting section and a protective-diode section by an insulating section,

wherein the insulating section electrically insulates the light-emitting section and the protective-diode section from one another in the area of the p-doped semiconductor layers,

wherein the area of the p-doped semiconductor layers is provided in the protective-diode section on the side facing away from the first pn junction with an n-doped semiconductor layer which forms a second pn junction with the area of p-doped semiconductor layers in the protective-diode section and is electrically conductively connected to the area of p-doped semiconductor layers in the light-emitting section, and

wherein the first pn junction in the area of the protective-diode section is short circuited.

18. (New) The light-emitting semiconductor component as claimed in claim 17, wherein an electrically conductive layer is applied to a side edge of the sequence of semiconductor layers facing the protective-diode section and electrically connects the area of n-doped semiconductor layers and the area of p-doped semiconductor layers with one another.